IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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Inventors:

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Assignee:

Nanometrics Incorporated

Title:

Apparatus And Method For The Measurement

Of Diffracting Structures

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Chih-Cheng Glen Kao

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COMMISSIONER FOR PATENTS Washington, D. C. 20231

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR §1.97(c)

Dear Sir:

Pursuant to 37 C.F.R. § 1.56, §1.97 and §1.98, the Applicants submit for consideration in the above-identified patent reexamination the documents listed on the accompanying Form PTO-1449. Copies of the documents are also submitted herewith. The Examiner is requested to make these documents of record.

This Information Disclosure Statement is submitted pursuant to 37 CFR §1.97(c) as it is after receipt of a first Office Action on the merits but before mailing of a final Action or Notice of Allowance. Accordingly, a fee is required pursuant to 37 CFR §1.17(p). A Fee Transmittal form (PTO/SB/17) is attached to this submission.

Applicants note that while the accompanying Form PTO-1449 cites documents labeled 1-45, previous Information Disclosure Statements have been submitted and the documents were labeled under a different labeling scheme.

Applicants would appreciate the Examiner initialing and returning the Form PTO-1449, indicating that the information has been considered and made of record herein. The Examiner is thanked for returning previously submitted Form PTO-1449s. Applicants

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note, however, that Form PTO-1449s included with Information Disclosure Statements submitted on January 3, 2002, January 30, 2002, and February 27, 2002 have not as yet been returned.

The information contained in this Information Disclosure Statement under 37 C.F.R. §1.555 is to the best of my knowledge and is not to be construed as a representation that: (i) a complete search has been made; (ii) additional information material to the examination of this application does not exist; (iii) the information, protocols, results and the like reported by third parties are accurate or enabling; or (iv) the above information constitutes prior art to the subject invention.

I hereby certify that this correspondence is being deposited with the United States Postal Service as Express Mail (Label No. EU 392 272 972 US) addressed to: Commissioner for Patents, Washington, D.C. 20231, on the below date.

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Date of Signature

Respectfully submitted,

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